

Vapor Phase Lubrication of Silicon MEMS

Michael T. Dugger¹, David B. Asay², James A. Ohlhausen¹ and Seong H. Kim²

¹ Materials Science and Engineering, Sandia National Laboratories

²Department of Chemical Engineering, The Pennsylvania State University

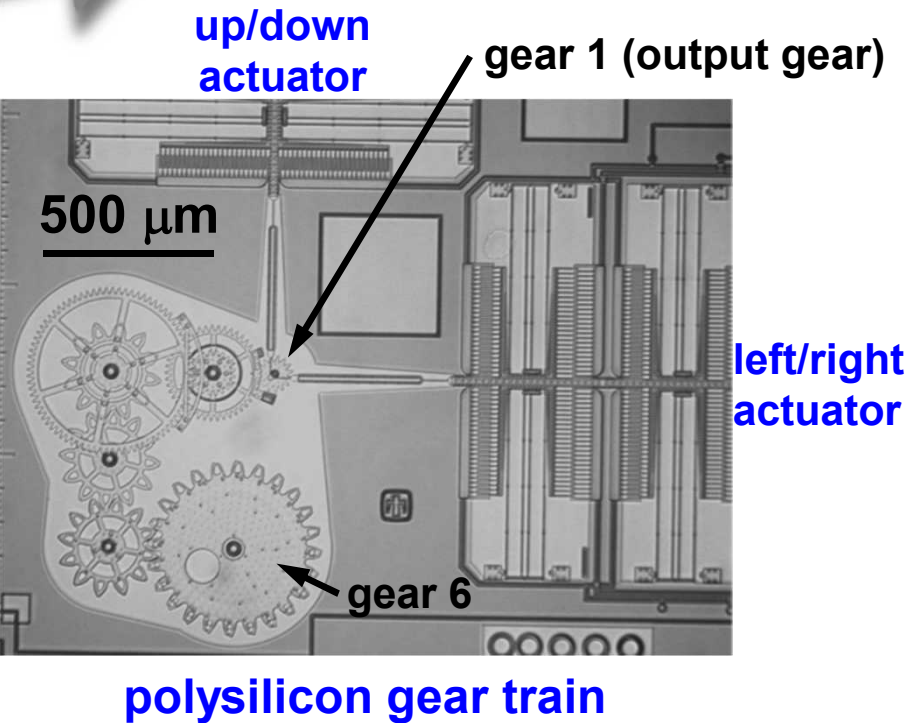
Materials Research Society, Fall 2007

26 November 2007

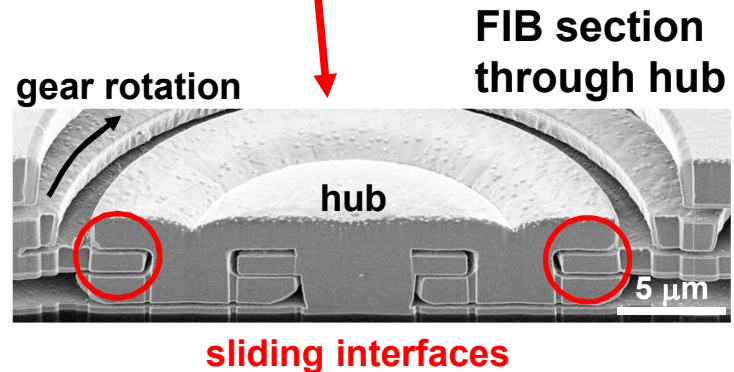
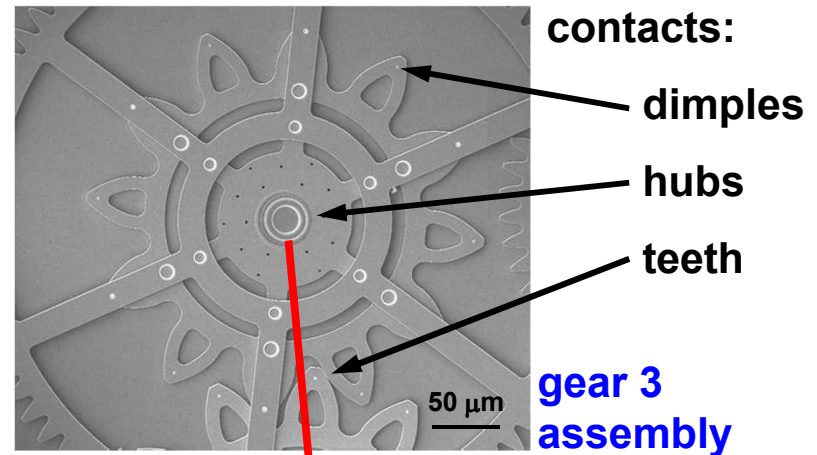
Boston, MA



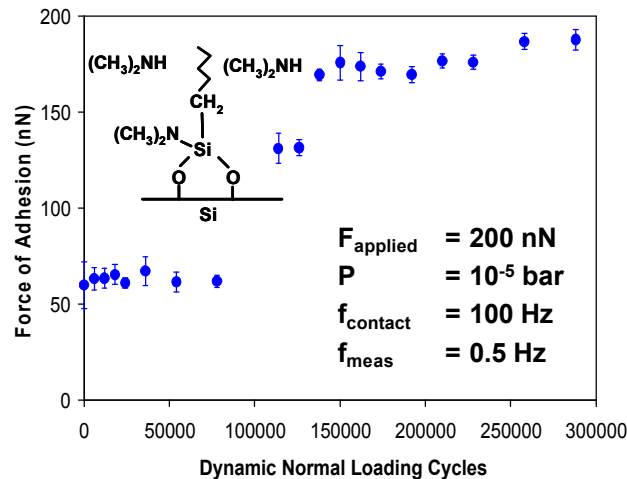
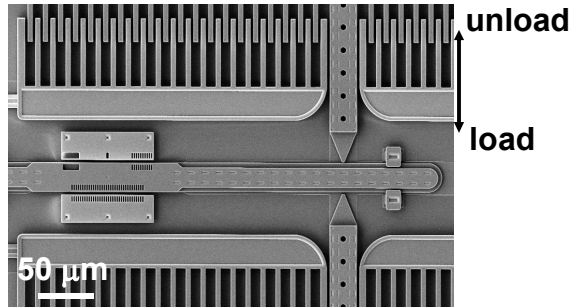
Fully-Assembled MEMS Limit Surface Treatment Options



- limited actuation and restoring forces
 - 1 μN to ~ 10 mN
- complexity afforded by multiple layers
 - deeply buried sliding surface



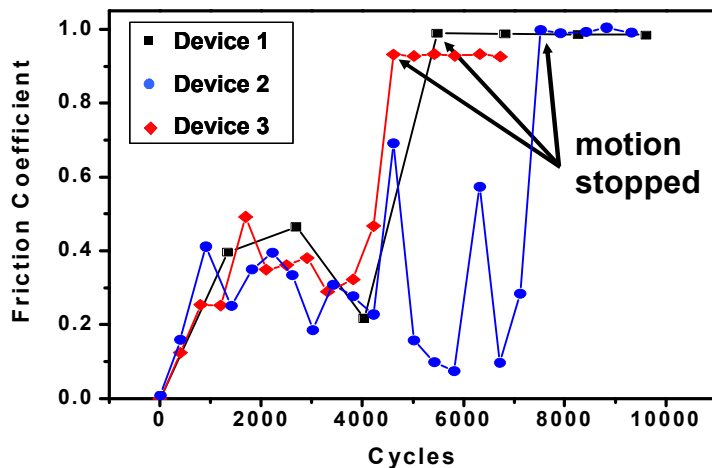
MEMS Failure Mode is a Function of the Device's Design



surface treatments are damaged easily, even for normal contact alone

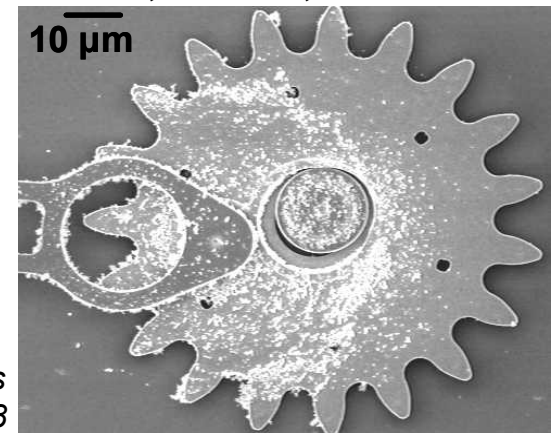
D.A. Hook, in preparation

$F_{\text{friction}} > F_{\text{actuation}}$



$F_{\text{actuation}} > F_{\text{friction}}$

600,000 rev, 1.8% RH



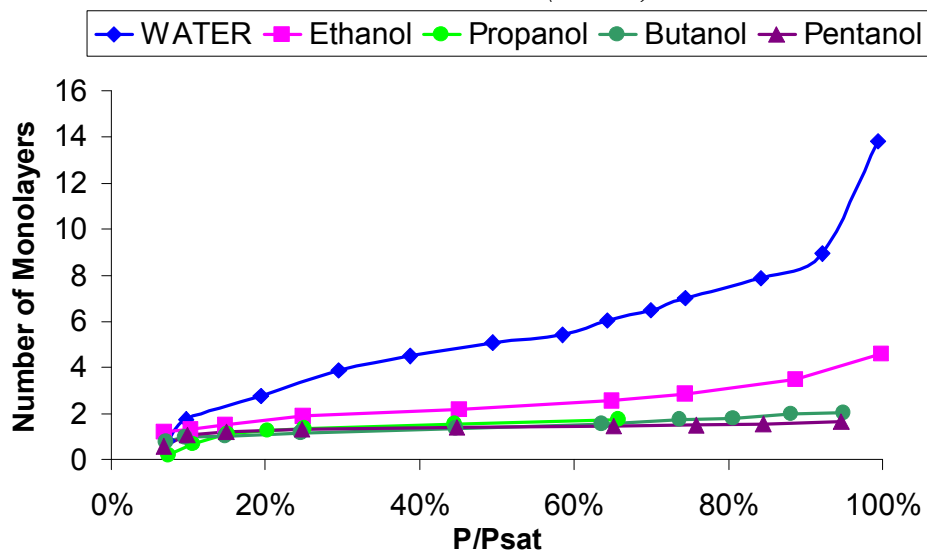
*D. Tanner et. al,
International
Reliability Physics
Symposium, 1998*



Sandia National Laboratories

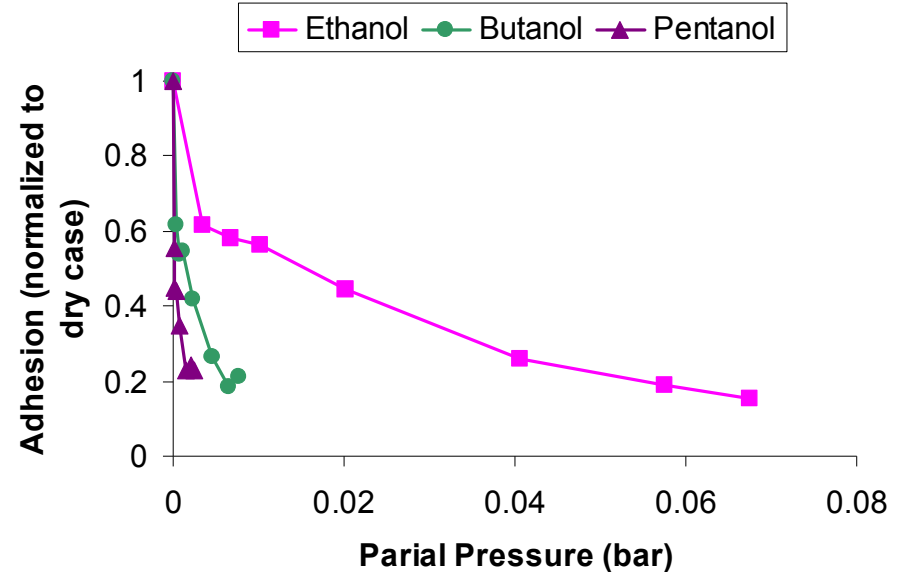
Alcohols Explored for Reducing Adhesion Between Silicon Surfaces

K. Strawhecker, D.B. Asay, J. McKinney and S.H. Kim, Trib. Lett. 19 (2005) 17-21.



ATR-FTIR measurement of adsorbed film thickness

- 1-3 monolayers at $0.1 < P/P_{\text{sat}} < 0.9$



AFM measurement of adhesion

- low concentrations significantly reduce adhesion

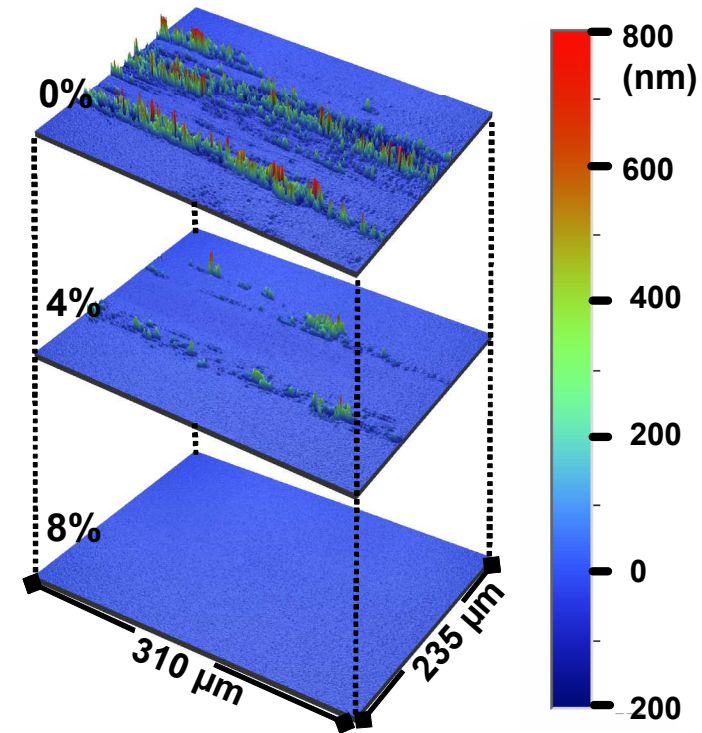
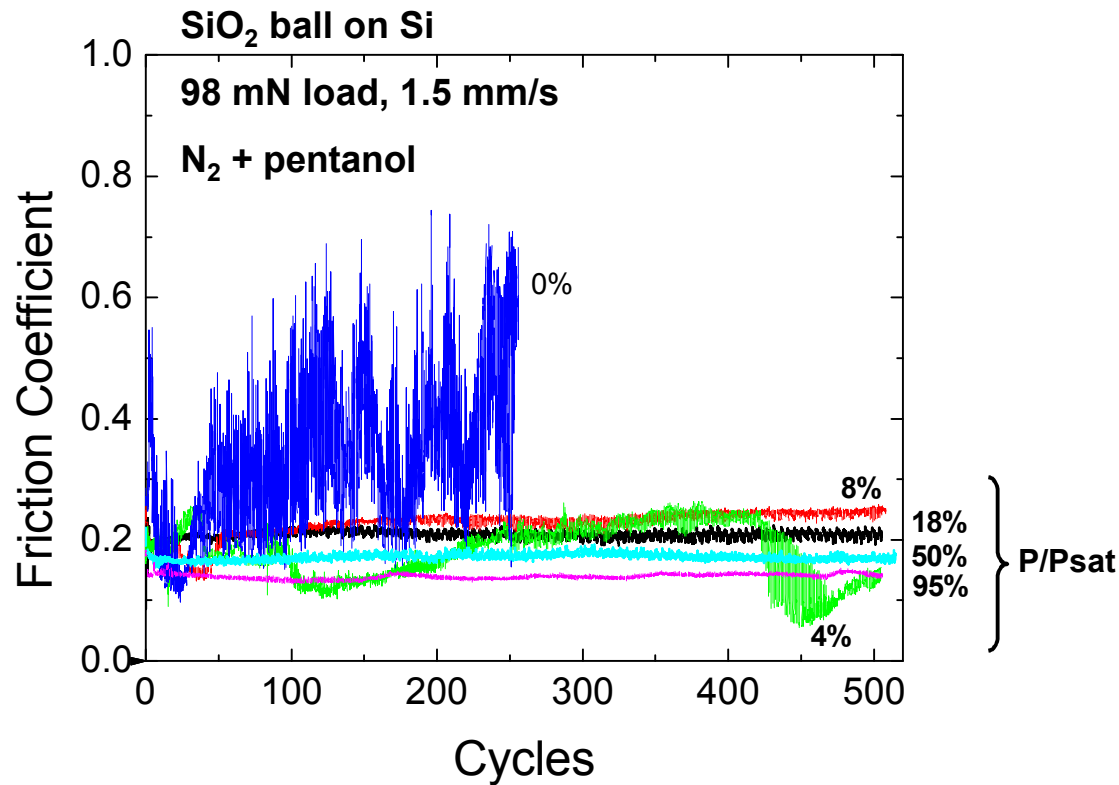
Lower surface tension, limited adsorbed film thickness, and high molar volume of alcohols limit capillary adhesion

*D.B. Asay and S.H. Kim,
Langmuir, in press*



Sandia National Laboratories

Vapor Phase Lubrication of Silicon Reduces Friction in Macroscale Sliding



No measurable wear for $P/P_{sat} \geq 8\%$

- corresponds to $\sim$ monolayer coverage from ATR-FTIR data

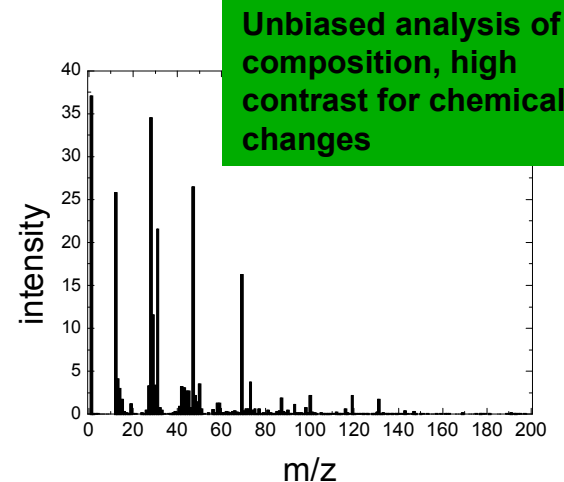
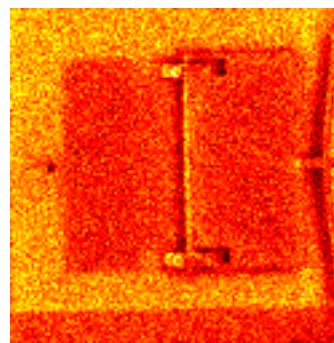
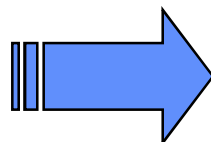
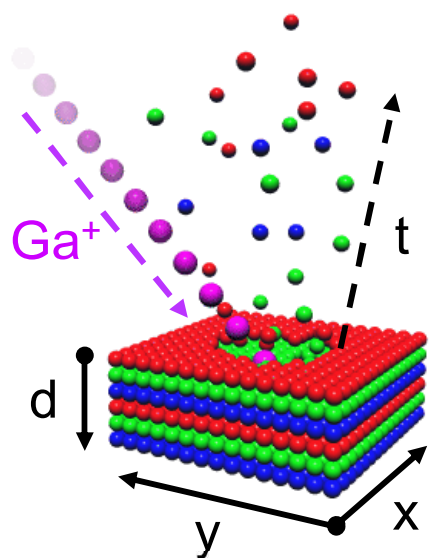
*D.B. Asay, M.T. Dugger, J.A. Ohlhausen
and S.H. Kim, Langmuir, in press*



Sandia National Laboratories

Multivariate Analysis Of SIMS Data Allows Detection of Subtle Changes In Chemistry

Time-of-Flight Secondary Ion Mass Spectroscopy (TOF-SIMS)
+ Automated eXpert Spectral Image Analysis (AXSIA)



$$D = C * S^T$$

The diagram illustrates the matrix equation $D = C * S^T$. On the left, a 3D cube labeled D represents the data. In the middle, a 3D cube labeled C represents the components. On the right, a 4x4 grid of 1D mass spectra labeled S^T represents the spectral data. The equation is shown with equals signs and plus signs between the matrices.

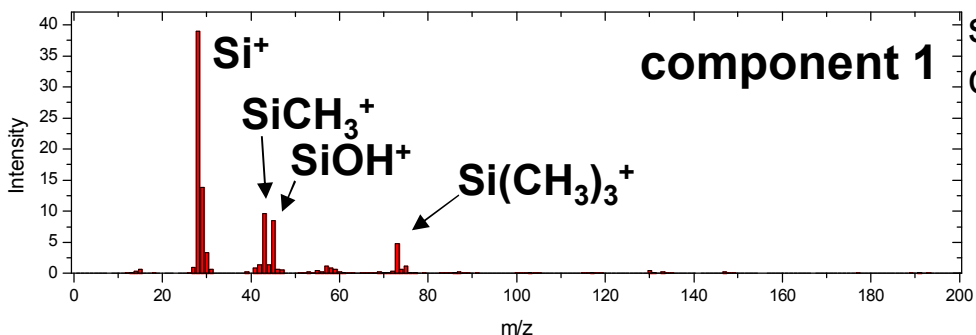
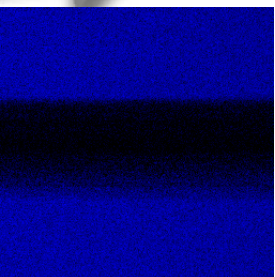
- solve $D = C * S^T$ using constrained alternating least squares
- constrain to physically realistic solutions
- number of components C is the minimum needed to reconstruct the original data, minus noise
- no bias or assumptions; rapidly identifies subtle changes

M. Keenan and P. Kotula, *Surf. Interface Anal.* **36** (2004) 2433.

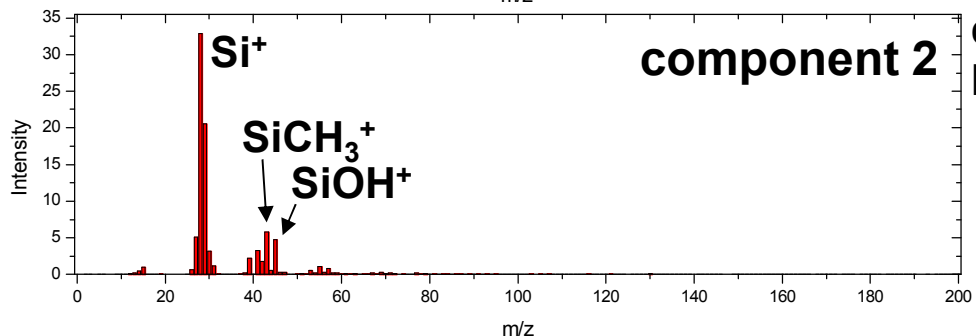
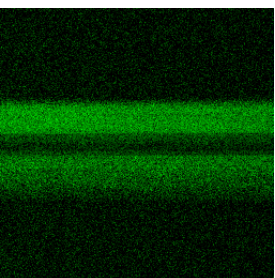


Sandia National Laboratories

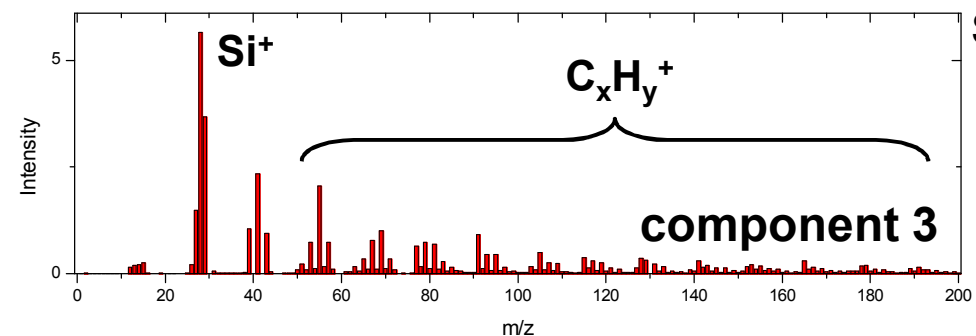
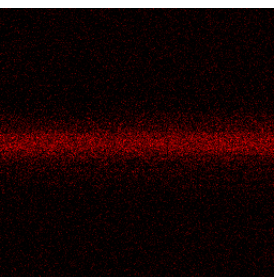
ToF-SIMS With Multivariate Analysis Shows Formation of High MW Product



surface oxides and contaminants (silicones)

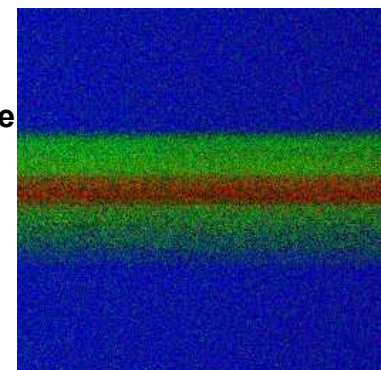


oxidized Si + short chain hydrocarbons



Si + long chain hydrocarbons

composite image

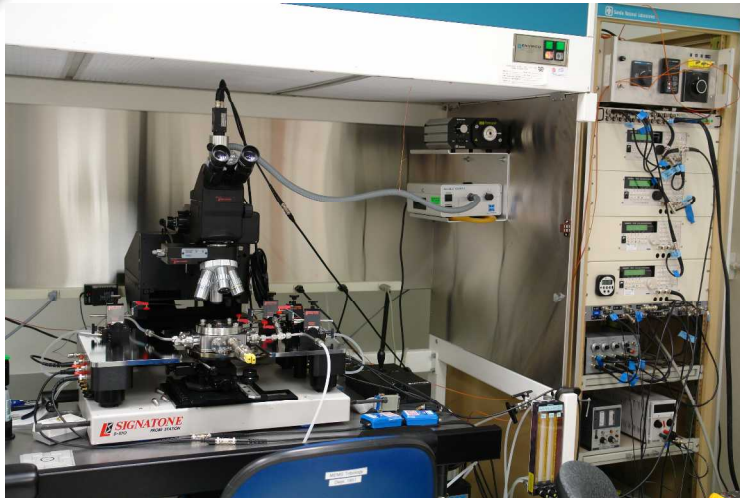


Reaction product forms *when, and where,* it is needed



Sandia National Laboratories

MEMS Device Testing in Controlled Environments

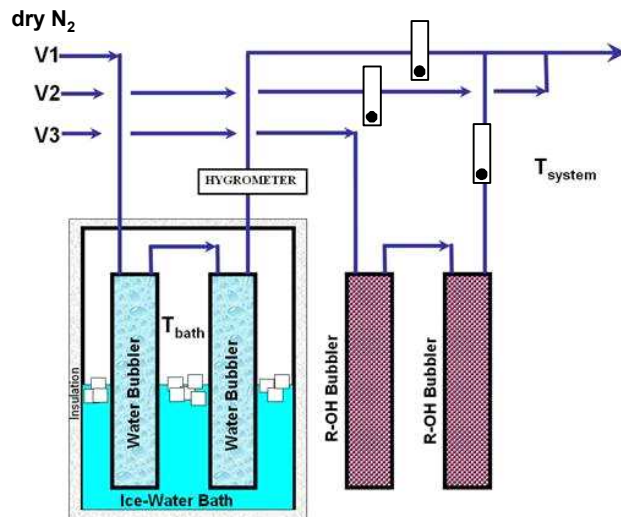


Device packaged in 24-pin DIP

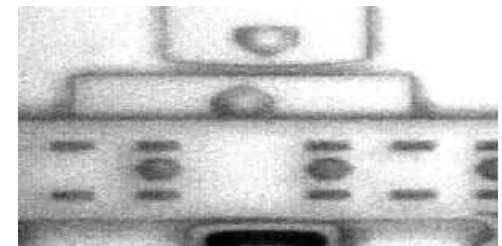
Process image data to give forces

- adhesion $F_{ad} = F_{unload} - F_{load} + F_r$
 $= a(V_c^2 - V_p^2) + kx$
- static friction $F_{fr} = F_{push} - F_{pull} - F_r$
 $= a(V_{slip}^2)$
- dynamic friction $F_d = k\Delta x$

Probe Station and Drive Electronics



Timed Image Capture
Displacement vs Input (V)



10 μ m

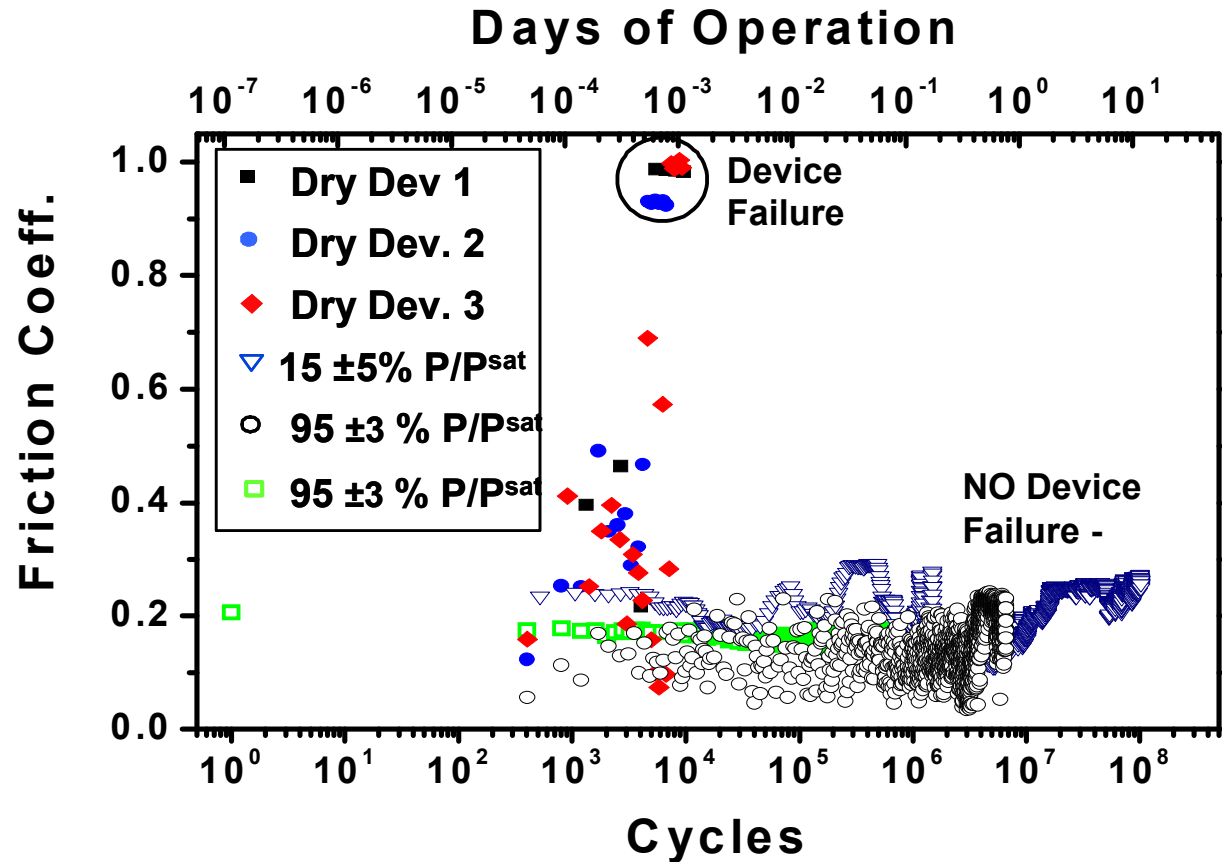
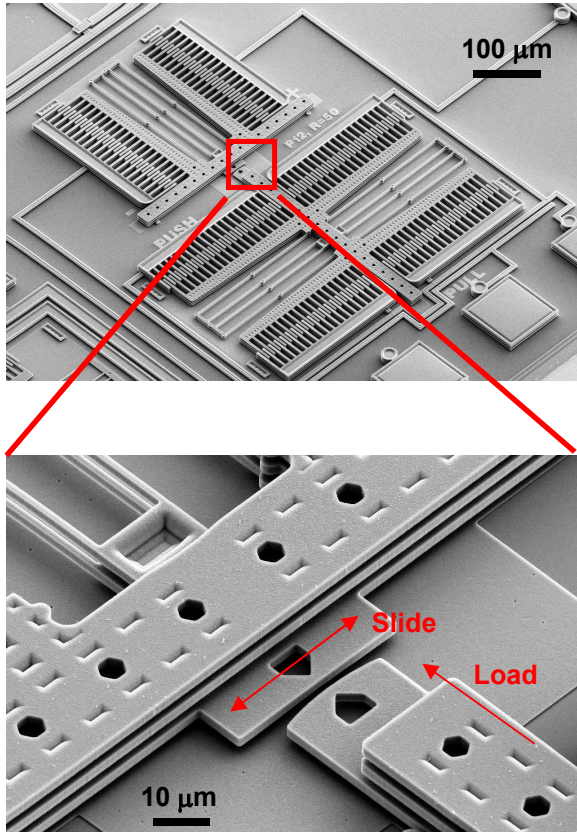
MEMS Environmental
Test Chamber



Sandia National Laboratories

Unprecedented Improvements in Operating Life are Observed with MEMS Tribometers

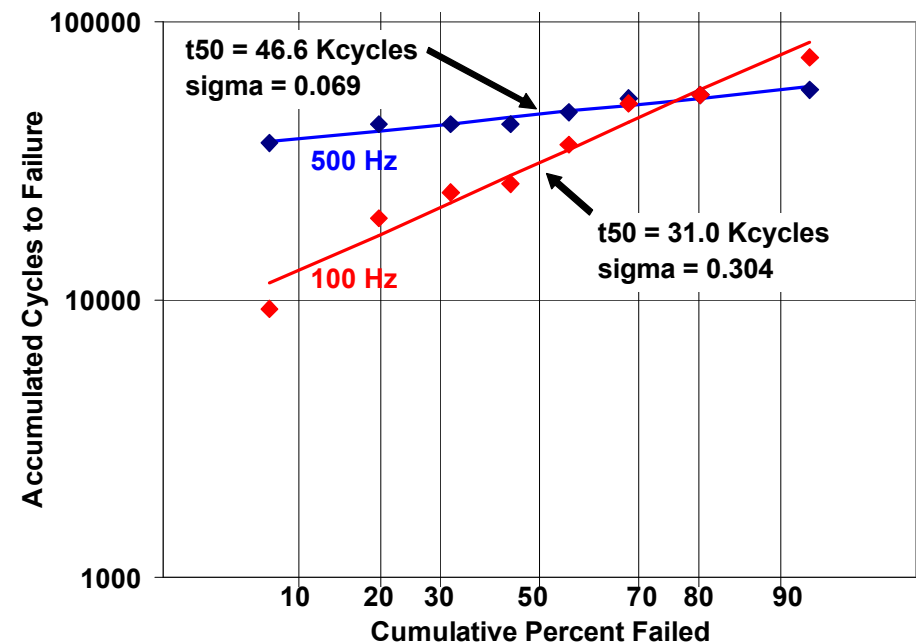
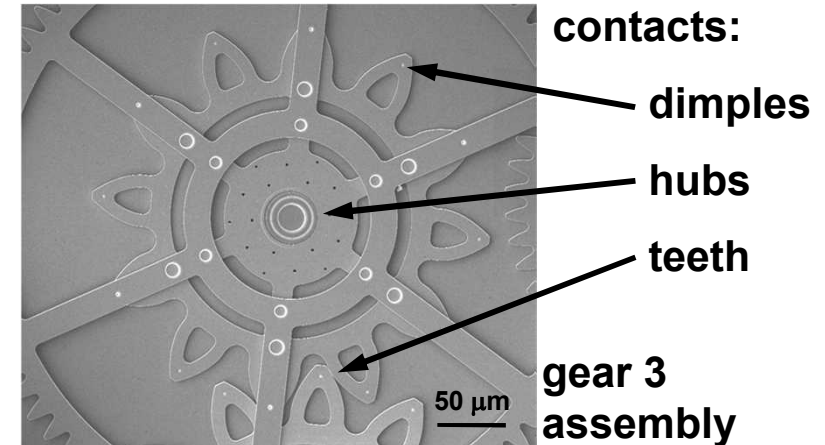
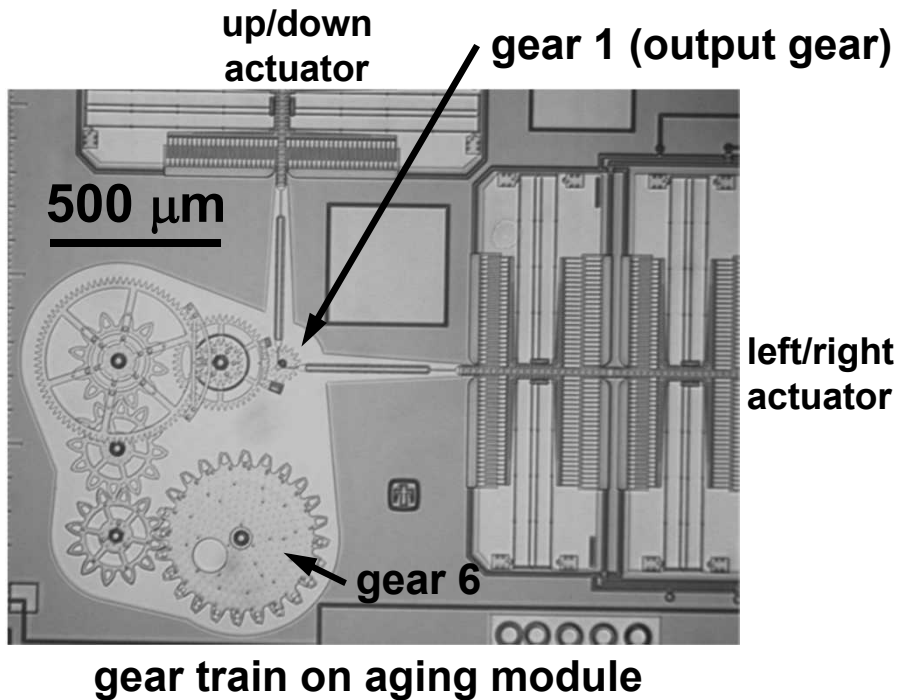
MEMS tribometer



- devices operated for 1-2 minutes at 100 Hz with CF₃-terminated monolayers alone
- no failure observed in > 10⁸ cycles with alcohol vapor present



Increased Operating Life of Gear Train with Vapor Phase Lubrication



FOTAS monolayer alone, $t_{50} = 4.7 \times 10^4$

With VPL, device was stopped at 4.8×10^8 cycles without failure

- 1000 ppmv pentanol, 0 H_2O



Vapor Phase Lubrication of Silicon by Tribochemical Reaction

S.M. Wiederhorn and D.E. Roberts, *Wear* **32** (1975) p.51-72

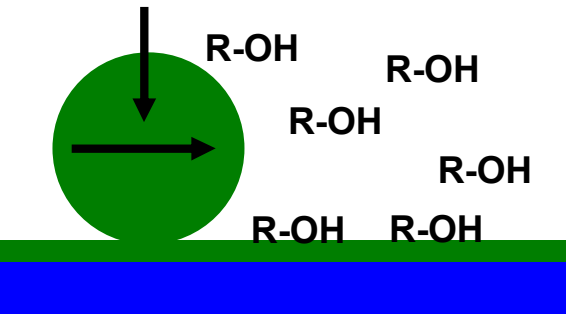
- reduced friction when abrading silicate glass in alcohols

Y. Hibi and Y. Enomoto, *Wear* **231** (1999) p.185-194

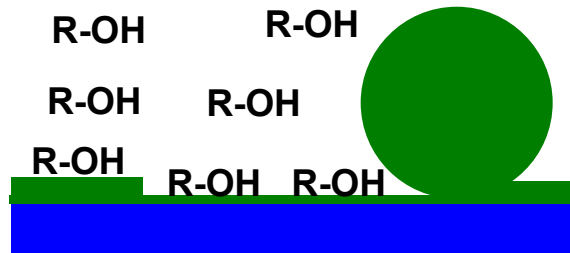
- alcohols reduce friction when cutting Si_3N_4
- very low wear rate in “higher” alcohols ($4 < n < 11$)

Y. Hibi, Y. Enomoto and A. Tanaka, *J. Mat. Sci. Lett.* **19** (2000) p.1809-1812

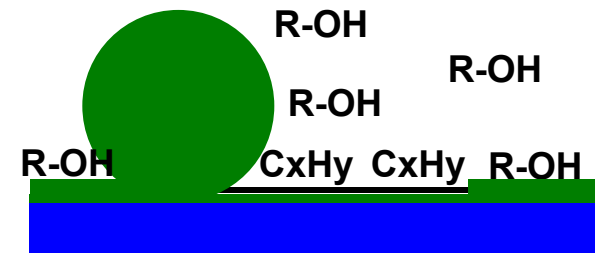
- postulate metal alkoxides condense to polymer and act as lubricant



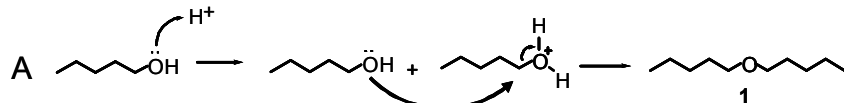
oxidized surface adsorbs alcohol



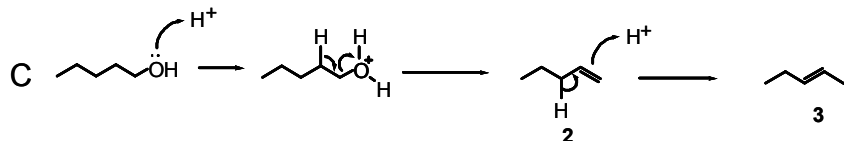
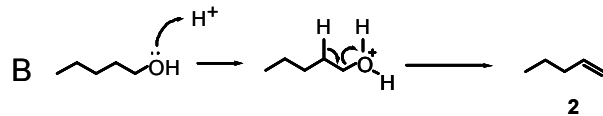
oxide wears, alcohol re-adsorbs



adsorbed species react to form high MW product

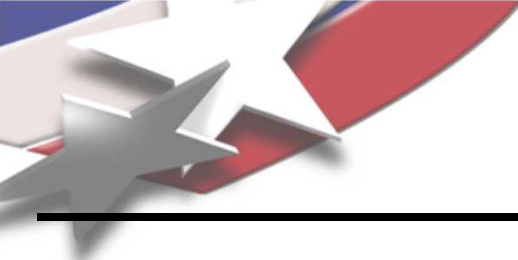


ethers?



olefins?





Summary

Vapor Phase Lubrication of silicon at room temperature has been demonstrated

- linear alcohol (pentanol) results in reduced wear
- ability to replenish lubricant film from the vapor phase

Reduced wear is accompanied by oligomer formation

- tribochemical reaction product forms at real contact locations
- suggests that thermionic emission or a catalytic surface are critical

Our paradigm about the reliability of MEMS devices with contacting surfaces must be revisited

